

**IN THE CLAIMS:**

This listing of claims will replace all prior versions and listings of claims in the application:

1. (Canceled)

2. (Previously Presented) A method for manufacturing a semiconductor device including a first element and a second element, comprising the steps of:

forming a gate electrode for each of the first element and the second element over a substrate having an insulating surface,

forming a gate insulating film over the gate electrode,

forming source and drain electrodes for each of the first element and the second element over the gate insulating film,

forming a first semiconductor film containing a first organic material over the source and drain electrodes of the first element,

forming a first mask over the first semiconductor film,

etching the first semiconductor film using the first mask to form a semiconductor layer of the first element,

forming a second semiconductor film containing a second organic material over the first mask and the source and drain electrodes of the second element,

forming a second mask over the second semiconductor film, and

etching the second semiconductor film using the second mask to form a semiconductor layer of the second element.

3. (Previously Presented) A method for manufacturing a semiconductor device including a first element and a second element, comprising the steps of:

forming a gate electrode of the first element over a substrate having an insulating surface,

forming a gate insulating film of the first element over the gate electrode of the first element,

forming source and drain electrodes of the first element over the gate insulating film of

the first element,

forming a first semiconductor film containing a first organic material over the source and drain electrodes of the first element,

forming a first mask over the first semiconductor film,

etching the first semiconductor film using the first mask to form a semiconductor layer of the first element,

forming a gate insulating film of the second element over the first mask and the drain electrode of the first element,

forming source and drain electrodes of the second element over the gate insulating film of the second element,

forming a second semiconductor film containing a second organic material over the source and drain electrodes of the second element,

forming a second mask over the second semiconductor film,

etching the second semiconductor film using the second mask to form a semiconductor layer of the second element, and

forming an insulating film over the second mask and the semiconductor layer of the second element.

4. - 5. (Canceled)

6. (Original) The method for manufacturing the semiconductor device according to Claim 2, wherein the first and second elements are included in a CMOS circuit.

7. (Original) The method for manufacturing the semiconductor device according to Claim 3, wherein one of the source and drain electrodes of the second element is connected to an EL element, and the first element, the second element, and the EL element are included in the same pixel.

8. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 2 or Claim 3, wherein the first mask and the second mask are formed by a

droplet discharge method.

9. (Original) The method for manufacturing the semiconductor device according to Claim 2 or Claim 3, the method further comprising:

- forming a first inorganic film over the first semiconductor film,
- forming a first barrier layer by etching the first inorganic film using the first mask,
- forming a second inorganic film over the second semiconductor film, and
- forming a second barrier layer by etching the second inorganic film using the second mask,

- wherein the first mask is formed over the first inorganic film,

- wherein the second mask is formed over the second inorganic film,

- wherein the semiconductor layer of the first element is formed by etching the first semiconductor film using the first mask after forming the first barrier layer, and

- wherein the semiconductor layer of the second element is formed by etching the second semiconductor film using the second mask after forming the second barrier layer.

10. - 11. (Canceled)

12. (Currently Amended) A method for manufacturing a semiconductor device comprising the steps of:

- forming a gate electrode over a substrate having an insulating surface;
- forming a first insulating film over the gate electrode;
- forming source and drain electrodes over the first insulating film;
- forming a semiconductor film containing an organic material over the source and drain electrodes;

- forming an inorganic film over the semiconductor film;

- forming a mask over ~~the semiconductor film~~ the inorganic film;

- etching the inorganic film using the mask to form a barrier layer;

- after forming the barrier layer, etching the semiconductor film using the mask to form a semiconductor layer; and

forming a second insulating film over the mask.

13. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 12, wherein the mask is formed by a droplet discharge method.

14. (Canceled)

15. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 2 or Claim 3, wherein each of the first mask and the second mask is formed by an organic material.

16. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 12, wherein the mask is formed by an organic material.

17. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 2 or Claim 3, wherein the etching steps are performed by O<sub>2</sub> ashing or O<sub>3</sub> ashing.

18. (Previously Presented) The method for manufacturing the semiconductor device according to Claim 12, wherein the etching step is performed by O<sub>2</sub> ashing or O<sub>3</sub> ashing.